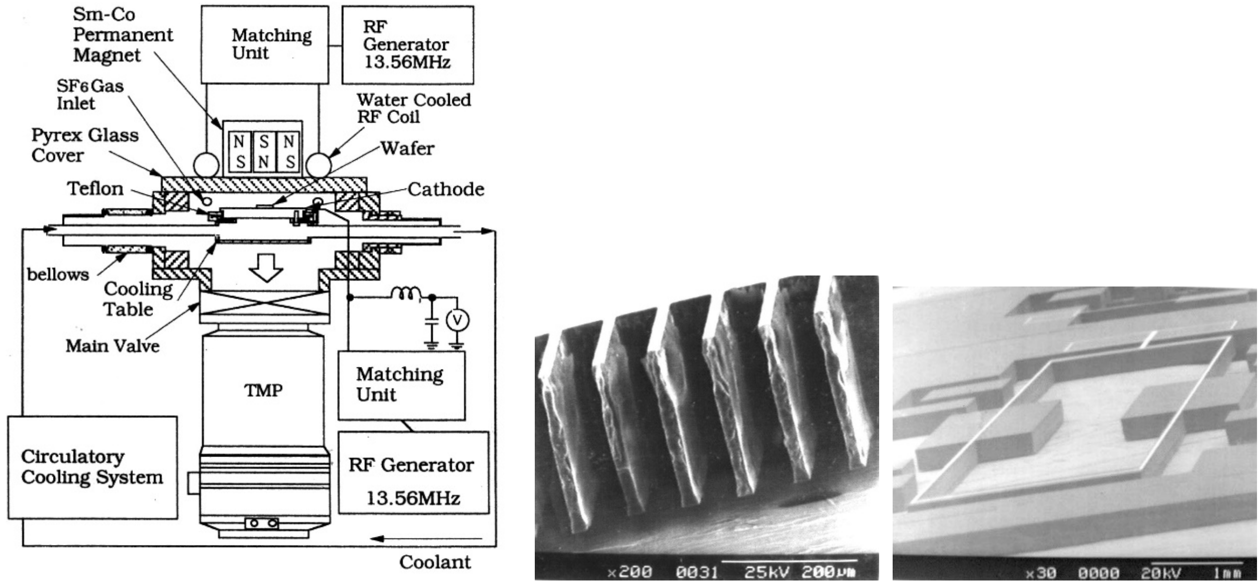
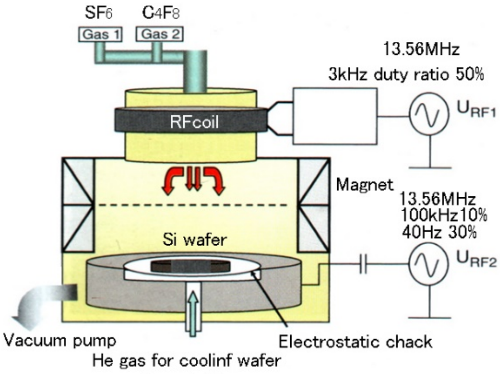
14 Deep reactive ion etching (Deep RIE) system

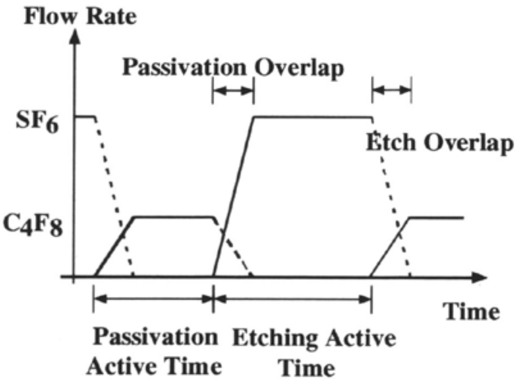


Low temperature Deep RIE system made in Tohoku Univ. and fabricated wafer for gyroscope (right)

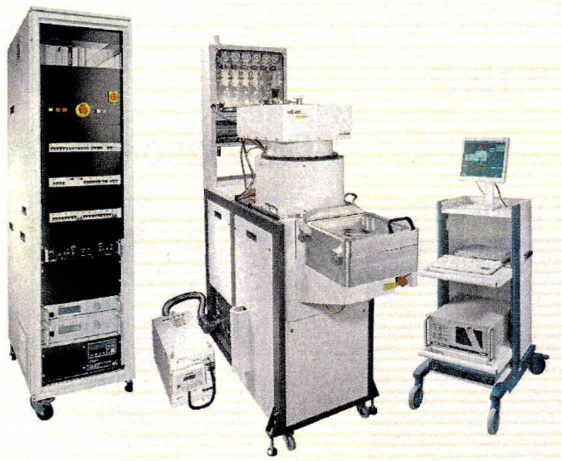
(M.Takinami, K.Minami and M.Esashi,11th Sensor Symposium, (1992) 15)



Deep RIE system



(F.Laermer (R.Bosch), Comprehensive Microsystems, Elsevier (2007) .217)



Deep RIE system displayed (Alcatel), Deep RIE system (Sumitomo Precision Product)